

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/826,054 Confirmation No. 9460
Applicant : Yao-Hwan Kao, et al.
Filed : April 16, 2004
TC/A.U. : 3753

Title : Adjustable Rinse Flow In Semiconductor Processing

Docket No. : N1085-00197 (TSMC2003-0309)
Customer No. : 08933

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AND RESPONSE

Sir:

In response to the Office Action of July 19, 2006, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks begin on page 4 of this paper.